	Title	Current OR	Current XRef
1	Apparatus for wafer level testing of a micromachined device	356/445	356/376 ; 356/382
2	Method for forming suspended micromechanical structures	438/734	216/2 ; 438/733 ; 438/739 ; 438/749 ; 438/753
3	Electrostatic microactuator and method for use thereof	310/309	361/283.3
4	Micromachined electrostatic vertical actuator	359/298	250/310 ; 310/328 ; 359/291 ; 361/283.1 ; 73/24.06
5	Micromechanical xyz stage for use with optical elements	359/392	310/309 ; 359/393
6	Fiber-optic free-space micromachined matrix switches	385/18	
7 ,	Surface acoustic wave filter with larger driving electrode areas in some parallel resonators, and	333/195	310/313D
8	Apparatus and method for optical scanning with an oscillatory microelectromechanical system	359/198	235/462.32 ; 359/199 ; 359/200 ; 359/201 ; 359/202 ; 359/212 ; 359/213 ; 359/214 ; 359/223
9	Surface acoustic wave resonance device adapted to simple and precise adjustment of resonant	333/193	310/313R ; 333/195
10	Free-space integrated micro-pickup head for optical data storage and a	369/112	359/362 ; 369/122 ; 385/14

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	U	1	Document	ID	Issue Date	Pages
1			US 6052197	Α -	20000418	10
2			US 6020272	Α	20000201	35
3	Ø		US 5998906	A	19991207	36
4			US 5969848	A	19991019	10
5	×		US 5963367	A	19991005	10
6	\boxtimes		US 5960132	A	19990928	18
7			US 5914646	A .	19990622	15
8			US 5867297	A	19990202	16
9			US 5694095	Α	19971202	11
10	⊠		US 5646928	А	19970708	12

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	L #	Hits	Search Text
1	L1	1736	comb with (actuator or driv\$4)
2	L3	46	(comb with (actuator or driv\$4))same (reflect\$4 or mirror)
3	L5	10	3 and electrostatic
4	L7	75	vertical adj1 comb